

Electronic Acknowledgement Receipt

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Title of Invention:	DRY ETCHING PROCESS FOR COMPOUND SEMICONDUCTORS
First Named Inventor/Applicant Name:	Jennifer Wang
Correspondence Address:	LaRiviere, Grubman & Payne, LLP - P.O. Box 3140 - Monterey CA 93942 US 8316498800 -
Filer:	Theresa JoAnn Wasilausky/Kathleen Galsford
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Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Fee Worksheet (PTO-06)	fee-info.pdf	8302	no	2

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If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.